Amendments to the Specification:

On page 1, at line 3, insert the following paragraph:

This application claims benefit of priority to French Patent Application No. FR 0215550 filed December 9, 2002.

On page 1, please replace the heading at line 3 with the following amended heading:

Technical field and prior art

TECHNICAL FIELD

On page 1, please insert the following heading at line 11:

BACKGROUND

On page 2, please replace the heading at line 31 with the following amended heading:

Summary of the invention

BRIEF SUMMARY

On page 8, please insert the following heading at line 17:

BRIEF DESCRIPTION OF THE DRAWING

On pages 8 and 9, beginning at line 22 on page 8, please replace the paragraphs with the following amended paragraphs:

[[-]] figure FIG. 1 is a graph showing the evolution of the stresses with temperature at the surfaces of the fused silica substrate within a conventional (silica

- + silicon) heterostructure,
- [[-]] figure FIG.2 is a similar graph showing the stresses at the surfaces of the silicon substrate of this heterostructure,
- [[—]] figure FIG. 3 is a diagram of a heterostructure 30 obtained by the method of the invention,
- [[-]] figures FIGs. 4 and 5 are graphs similar to those of figures FIG.s 1 and 2 showing the evolution of the stresses with temperature within a heterostructure stressed by the method of the invention,
- [[-]] figure FIG. 6 is a diagram of one non—limiting embodiment of the method of the invention,
- [[-]] figures FIG.s 7, 8 and 9 show different ways of stressing basic structures to be assembled,
- [[-]] figures FIGs. 10A and I0B show from above two examples of producing one of the structures to be assembled in such a way as to prevent trapping air bubbles, and
- [[—]] figure FIG. 11 is a diagrammatic view in section of a pair of deformable preforms.

On page 9, please replace the heading at lines 9 and 10 with the following amended heading:

Detailed Description of embodiments of the invention

DETAILED DESCRIPTION